1FW 1762

Attorney's Docket No. 5308-157IP2

<u>PATENT</u>

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Pre: Das et al.

Berial No.: 10/045,542

Filed: October 26, 2001

Confirmation No.: 3570 Group Art Unit: 1762 Examiner: Kirsten Jolley

METHOD OF FABRICATING AN OXIDE LAYER ON A SILICON CARBIDE

LAYER UTILIZING AN ANNEAL IN A HYDROGEN ENVIRONMENT

Date: January 28, 2005

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

AMENDMENT

Sir:

For:

Applicants provide the present Amendment to address the issues raised in the Official Action mailed October 28, 2004.

It is not believed that an extension of time and/or additional fee(s)-including fees for net addition of claims-are required, beyond those that may otherwise be provided for in documents accompanying this paper. In the event, however, that an extension of time is necessary to allow consideration of this paper, such an extension is hereby petitioned under 37 C.F.R. §1.136(a). Any additional fees believed to be due in connection with this paper may be charged to our Deposit Account No. 50-0220.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 6 of this paper.